



제 30회 한국반도체학술대회

The 30th Korean Conference on Semiconductors

2023년 2월 13일(월) ~ 15일(수) | 강원도 하이원리조트(그랜드호텔 컨벤션타워)

2023년 2월 14일(화), 10:55-12:40

Room J (하트 III, 6층)

Q. Metrology, Inspection, Analysis, and Yield Enhancement 분과

[TJ2-Q] Metrology, Inspection, Analysis, and Yield Enhancement II

좌장: 강상우 소장(한국표준과학연구원), 정용우 TL(SK 하이닉스)

TJ2-Q-1 10:55-11:10	X-Ray Fluorescence (ED-XRF) 및 X-Ray Diffraction (XRD) 측정 기술을 활용한 3D NAND Word Line W Recess 변화 계측 기술 개발 Young Chan Kim <i>Manufacturing Technology, SK Hynix</i>
TJ2-Q-2 11:10-11:25	Continuous Angular Mueller Matrix Ellipsometry for Nanostructure Metrology Daehoon Han, Garam Choi, Jinyong Kim, Young-Uk Jin, Jinseob Kim, Jaehwang Jung, Seungwoo Lee, Jinwoo Ahn, Taejoong Kim, Wookrae Kim, Myungjun Lee, and Changhoon Choi <i>FAB Equipment R&D Team⁴, Mechatronics Research, Samsung Electronics Co., Ltd.</i>
TJ2-Q-3 11:25-11:40	Improvement of Instrumentation Consistency Using DUV Filter In Spectroscopic Ellipsometry 김유성, 정용우 <i>DRAM M¹⁴ Metrology Inspection Team, Manufacturing Technology, SK Hynix</i>
TJ2-Q-4 11:40-11:55	이온빔 기반 패턴 및 검사장비를 위한 가스장 이온원의 개발 박인용, 이하림, 타카시 오가와, 정해원, 윤달재, 김지수, 강훈, 황준혁 <i>한국표준과학연구원 첨단측정장비연구소 연구장비성능평가팀</i>
TJ2-Q-5 11:55-12:10	In-situ Liquid Cell TEM Real-time Images Examine for Water Splitting Using g-C₃N₄ Semiconductor Hetero-structures with Efficient Charge Separation V. Navakoteswara Rao, Jung Ho Yoo, Yonghee Lee, Chi Won Ahn, and Jun-Mo Yang <i>Nano-Convergence Technology Division, NNFC</i>
TJ2-Q-6 12:10-12:25	Dynamic Interferometry for 3D Inspection of Multi-stacked Thin Films Young-Sik Ghim ^{1,2} and Hyug-Gyo Rhee ^{1,2} <i>¹KRISS, ²University of Science and Technology (UST)</i>
TJ2-Q-7 12:25-12:40	Thermo-reflectance Microscope for Thermal Measurement of Microelectronic Circuit Guesuk Lee and Byongjin Ma <i>KETI</i>